Indigenous Development of Scanning Electron Microscope

Security Electronics & Software Systems Division Bhabha Atomic Research Centre, Mumbai

Scanning Electron Microscope (SEM) is a scientific instrument that uses a finely focused beam of electrons to provide information about topography, elemental contrast and characterization of a specimen. Over the past few decades, it has proved to be an indispensable tool for research and education in material science, chemistry, biological sciences, life sciences, forensics and nanotechnology. SEMs are currently imported at costs unaffordable for most educational institutions in India. Bhabha Atomic Research Centre, Mumbai has developed an indigenous SEM. The SEM comprises mostly of in-house designed and developed subsystems and a few commercial off-the-shelf components. With growing impetus for indigenous development of technology under the flagship of the Make in India initiative by the Indian Government, development of SEM is expected to contribute significantly towards technological advancement in the country.

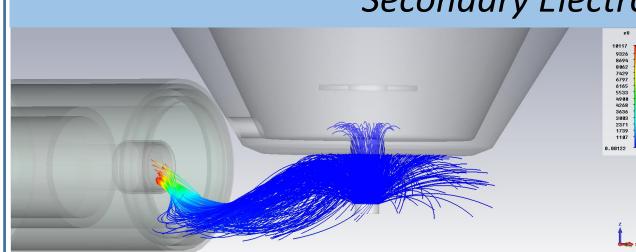


with grid	bias vo	Itage and
floating	filament	heating
supplies.		

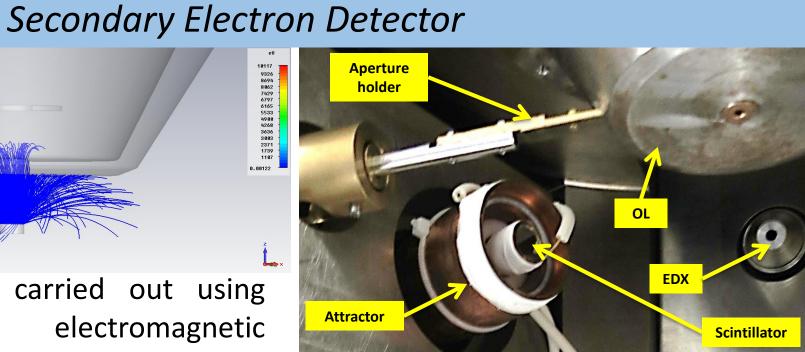
Max acceleration voltage
Acceleration voltage ripple
Acceleration voltage stability
Max electron emission current
Max grid bias voltage

Max acceleration voltage	:30 KV
Acceleration voltage ripple	:10 ppm
Acceleration voltage stability	:100 ppm/ł
Max electron emission current	:300 μA
Max grid bias voltage	:2 KV

> Demagnification and focusing of electron beam achieved using multiple rotationally symmetric Iron clad magnetic lenses. Magnetic core material : Pure Iron > Deflection coil assembly: X & Y dipoles with Mn-Zn ferrite core > Octopole for astigmatism correction



> Design optimization carried out using computational electromagnetic



BARC SEM Specifications

- Electron Source
- Vacuum pressure
- SEM Resolution
- Magnification
- Acceleration Voltage
- Sample Stage
- Sample size
- In-house Detector
- > Optional attachment
- : Thermionic Tungsten Filament : 10⁻⁶ Torr.
- : < 20nm
 - : 50x to 1,50,000x
- : 1 kV to 30 kV
 - : 5-axis Motorized
 - : 50mm dia., 40mm height
 - : Secondary Electron

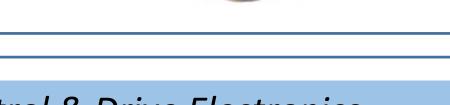
Software for centralized control and Image post-processing

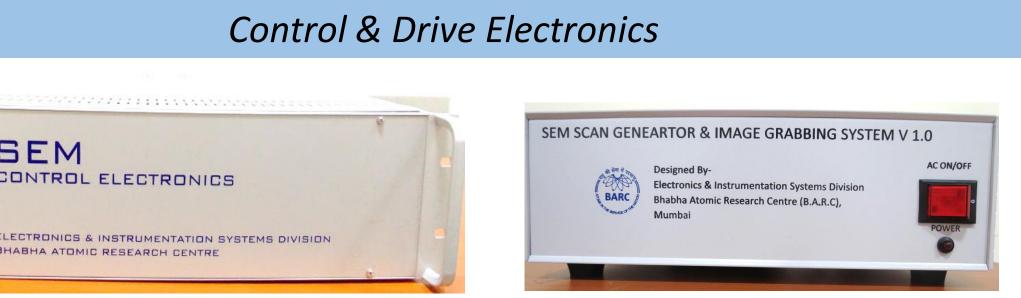
: EDX Detector (Commercial)

100 µm dia. Circularity: 2%

SEM

CONTROL ELECTRONICS





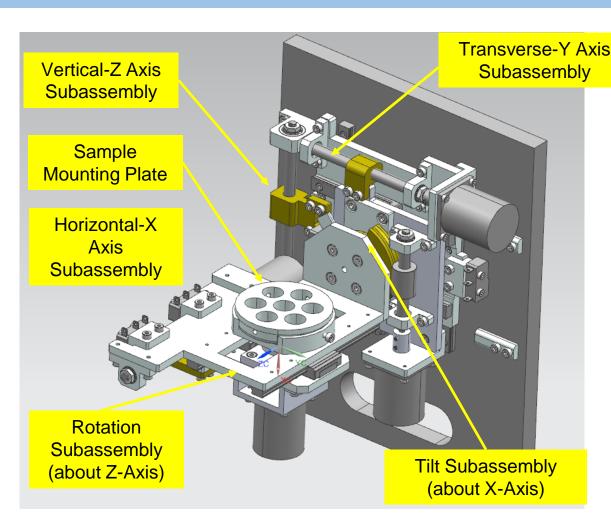
> Microcontroller based integrated SEM control & drive electronics. > Lens drive modules > Vacuum system control Detector control Data acquisition & Signal processing modules

X-scan signal frequency: 5 KHz Y-scan signal frequency: 20 Hz Live rate: 10 fps (500 X 400) > Acquisition rate: 2.5 mins/frm. (1000 x 800) > No of acquisition channels : 2

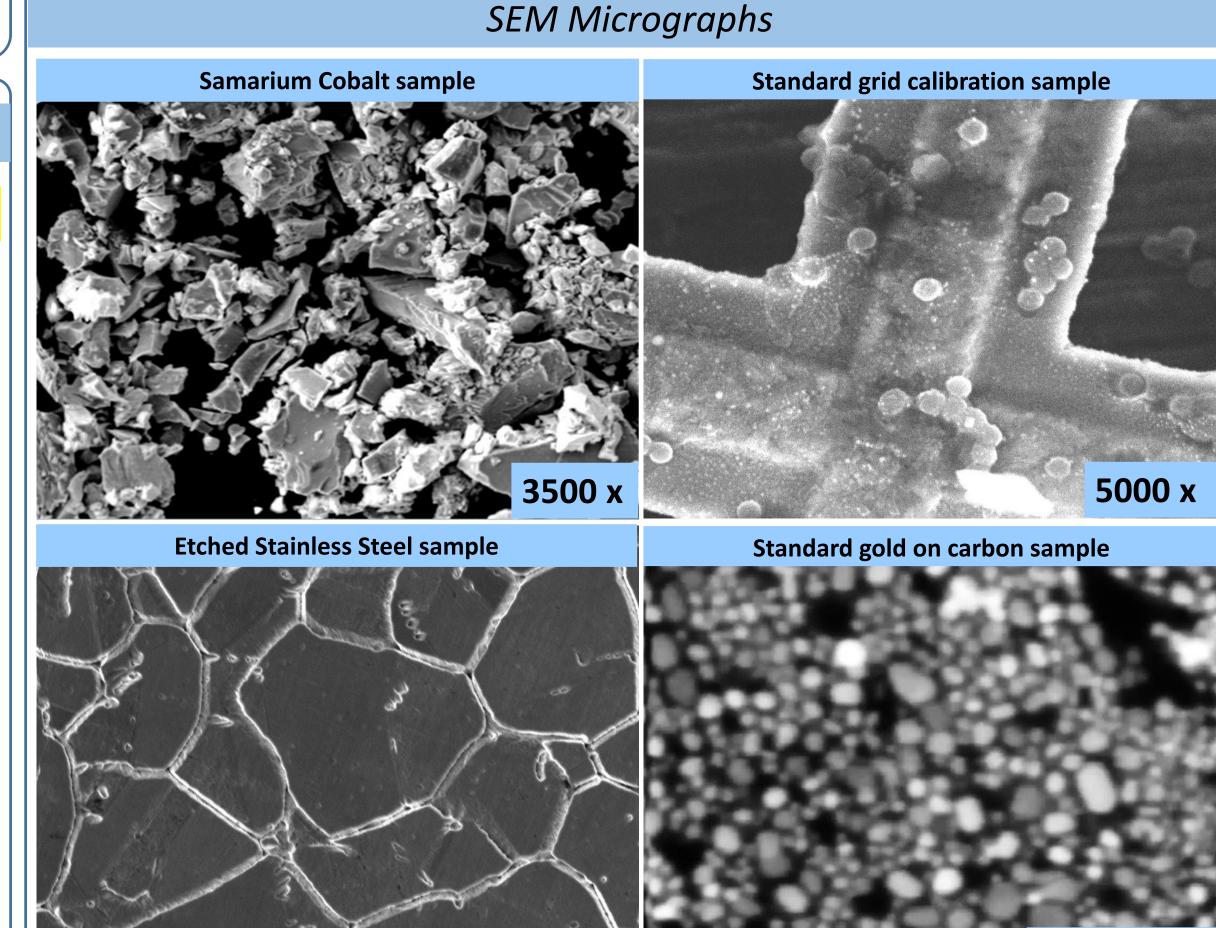
simulation to maximize detector		
collection efficiency	SE Detector Type	: ET-type
Simulation results	Scintillator	: YAP:Ce
 Collection efficiency at WD=8mm: 50 % 	Scintillator voltage	: +10kV
 Collection efficiency at WD=40mm: 99 % 	Faraday cage voltage	: ±1kV

SEM vacuum chamber & Sample Stage



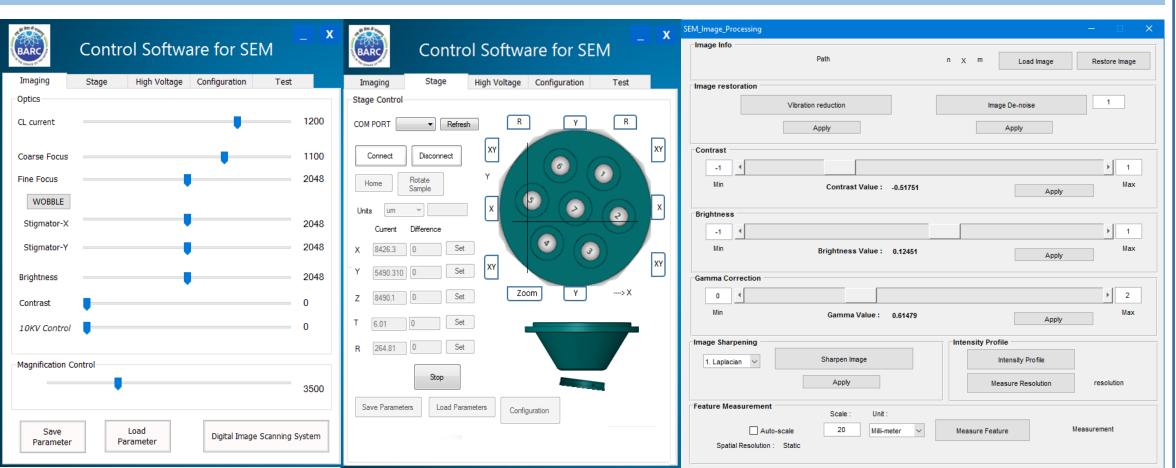


Material	: AISI 1018	≻ 5-DOF	: Motorized
➢ No. of ports	: 8	≻X	: ± 20 mm
Surface passivation	: Ni plating	≻ Y	: ± 20 mm
Sliding door mechanism holds the sample stage		≻Z	: 8 - 40 mm
		≻ Tilt	: ± 45°
		Rotation : 360°	



Sample stage motion control

Software



> Integrated GUI based software for imaging, stage motion and HV control

- Safety interlock provided for HV power supplies provided with vacuum level and voltage ramp rate.
- SEM image post-processing software with provisions for denoising, image enhancement and meteorology.
- Prototype auto-focussing software has been developed.



L,50,000 x

8000 x